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**RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2766**

PATENT  
Attorney Docket No. 99154X204201

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:

Fang et al.

Application No. 09/595,227

Filed: June 16, 2000

For: **METHOD FOR POLISHING A  
MEMORY OR RIGID DISK WITH A  
PHOSPHATE ION-CONTAINING  
POLISHING SYSTEM**

Art Unit: 2766

Examiner: Hadi Shakeri

pls.  
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a/s

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TECHNOLOGY CENTER R3700

**RESPONSE TO OFFICE ACTION**

Commissioner for Patents  
Box AF  
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated June 13, 2002, please enter the following amendments and consider the following remarks.

**AMENDMENTS**

**IN THE CLAIMS:**

Please replace the indicated claims as follows:

1. (Amended) A method for planarizing or polishing a surface of a memory disk comprising abrading at least a portion of the surface with a polishing system comprising (i) a polishing composition comprising water, an oxidizing agent, and about 0.04 M or higher phosphate ion or phosphonate ion, and (ii) abrasive material.
  
4. (Amended) The method of claim 1, wherein the surface of the memory disk comprises nickel-phosphorus.